

Electronic Acknowledgement Receipt

EFS ID:	1283109
Application Number:	10828596
International Application Number:	
Confirmation Number:	5520
Title of Invention:	Methods of forming metal thin films, lanthanum oxide films, and high dielectric films for semiconductor devices using atomic layer deposition
First Named Inventor/Applicant Name:	Ki-yeon Park
Customer Number:	20792
Filer:	Shawna Cannon Lemon/Sarah Abraham
Filer Authorized By:	Shawna Cannon Lemon
Attorney Docket Number:	5649-1286
Receipt Date:	31-OCT-2006
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Application Type:	Utility

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File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part /.zip	Pages (if appl.)
1	Response to Election / Restriction Filed	5649-1286_Election_10828596.pdf	114683	no	2

Warnings:

Information:**Total Files Size (in bytes):**

114683

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New Applications Under 35 U.S.C. 111

If a new application is being filed and the application includes the necessary components for a filing date (see 37 CFR 1.53(b)-(d) and MPEP 506), a Filing Receipt (37 CFR 1.54) will be issued in due course and the date shown on this Acknowledgement Receipt will establish the filing date of the application.

National Stage of an International Application under 35 U.S.C. 371

If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.